Author Index of Volume 39

Ahlers, H., 117
Asakura, S., 231

Baizar, R., 125
Baumann, H., 169
Bergqvist, J., 191
Bernabeu, E., 25
Bogdanova, N., 125
Bohrisch, R., 117
Boldt, J., 117
Boursas, A., 19
Bouwstra, S., 149

Chung, G.-S., 241
Churenkov, A.V., 141
Crazzolara, H., 201

Dekhtyaruk, N.T., 237
de Rooij, N.F., 83
Dideikin, A.T., 7
Dietrich, D., 259
Dimitrov, D.B., 45
Đonlagić, D., 111
Döring, C., 169

El-hami, M., 181
El Jai, A., 95

Esashi, M., 209
Escudero, J.L., 25

Finkelstein, L., 181
Flach, G., 201
Frühauf, J., 259

Ganyuk, L.N., 237
Goebel, H., 169
Grattan, K.T.V., 181
Grauer, T., 169
Guerrero, H., 25

Helmig, V., 117
Hietanen, J., 129
Hjort, K., 133

Ignatkov, V.D., 237
Ishihara, A., 231

Jackson, D.A., 219
Jaecklin, V.P., 83

Kerns, D., 225
Koprivnikar, J., 111
Krasnogenov, E., 125
Kwaaitaal, Th., 103

Lachinov, A.N., 1
Lee, A.P., 73
Linder, C., 83
Luukkala, M., 129

Matko, V., 111
Matsumoto, Y., 209
Mattila, P., 129
Mettner, M., 169
Michelena, M., 55
Moret, J.-M., 83

Nagendra, C.L., 59
Nagy, A., 55
Nedev, N., 19
Ning, Y.N., 219

Palmer, A.W., 181
Pisano, A.P., 73

Rodriguez, P., 55

Sasaki, K., 129
Schmidt, W.-D., 117
Simon, M.C., 95
Smirnov, N., 19
Söderkvist, J., 133

Spiering, R.M.E.J., 149
Spiering, V.L., 149
Stemme, E., 159
Stemme, G., 159
Stor-Pellinen, J., 129

Thutupalli, G.K.M., 59
Trah, H.-P., 169
Trujillo, H., 55
Tsuzuki, F., 129
Tu, X.-Z., 49

Ugarte, R., 55
Umadevi, P., 59

Vainberg, V.V., 237
von Münch, W., 201
Vorobkalo, F.M., 237
Voronin, V., 125
Vul', A.Ya., 7

Wie, C.R., 253

Yu, L.Z., 253

Zarubin, L.I., 237
Zemel, J.N., 49
Zerrik, E., 95

Subject Index of Volume 39

Accelerometer
piezoresistive accelerometer with overload protection and low cross-sensitivity, 201
integrated silicon capacitive accelerometer with PLL servo technique, 209

Bimorph cantilever
micromachined valve with hydraulically actuated membrane subsequent to a thermoelectrically controlled bimorph cantilever, 169
Bulk-glass sensing elements
review of optical current sensors using bulk-glass sensing elements, 219

Cadmium
magnetic-field sensor using plastic optical fiber and polycrystalline CdMnTe, 25
Carbon fibres
thermometric characteristics of carbon fibres, 237
Classification of sensors
expert system application using optical-fibre sensor classification data, 181
CMOS technology
integrated photocapacitive position-sensitive detector made in CMOS technology, 117
Comb actuator
comb actuators for *xy*-microstages, 83
Condenser microphone
finite-element modelling and characterization of a silicon condenser microphone with a highly perforated backplate, 191

Decision-aiding
expert system application using optical-fibre sensor classification data, 181
Distributed systems
regional observability and sensor structures, 95
Dual-emitter dual-base structure
investigation of the magnetosensitivity of a dual-emitter dual-base structure in oscillator mode of operation, 19

Electrostatic ultrasonic air transducer
a Helmholtz resonator model for an electrostatic ultrasonic air transducer with a V-grooved backplate, 129
Expert systems
expert system application using optical-fibre sensor classification data, 181

Faraday-effect sensor
magnetic-field sensor using plastic optical fiber and polycrystalline CdMnTe, 25
Field-effect transistor
low-power single FET frequency-response magnetometer, 45
Finite-element modelling
finite-element modelling and characterization of a silicon condenser microphone with a highly perforated backplate, 191

Flexural vibrations
flexural vibrations in piezoelectric semi-insulating GaAs, 133
Fluid pump
a valveless diffuser/nozzle-based fluid pump, 159

Gallium arsenide
flexural vibrations in piezoelectric semi-insulating GaAs, 133

Helmholtz resonator
a Helmholtz resonator model for an electrostatic ultrasonic air transducer with a V-grooved backplate, 129

Impact testing
repetitive impact testing of micromechanical structures, 73
Integrated circuits
thin SOI structures for sensing and integrated circuit applications, 241
Iron
application of oscillation phenomenon in $Fe/H_3PO_4–H_2O_2$ system to a thermal sensor, 231

Magnetic-field sensor
investigation of the magnetosensitivity of a dual-emitter dual-base structure in oscillator mode of operation, 19
magnetic-field sensor using plastic optical fiber and polycrystalline CdMnTe, 25
Magnetometer
low-power single FET frequency-response magnetometer, 45
Magnetotransistors
diode-connected magnetotransistors, 55
Manganese
magnetic-field sensor using plastic optical fiber and polycrystalline CdMnTe, 25
Measurements
regional observability and sensor structures, 95
Micromachining
micromachined valve with hydraulically actuated membrane subsequent to a thermoelectrically controlled bimorph cantilever, 169
Micromechanical structures
repetitive impact testing of micromechanical structures, 73
Micropump
a valveless diffuser/nozzle-based fluid pump, 159
Microresonators
photothermal excitation and self-excitation of silicon microresonators, 141
MIS structure
photodetectors based on metal–tunnel insulator–semiconductor structures, 7

Optical current sensors
review of optical current sensors using bulk-glass sensing elements, 219

Optical fiber
magnetic-field sensor using plastic optical fiber and polycrystalline CdMnTe, 25
vertical-membrane optical-fiber pressure sensor, 49
Orientation-dependent etching
computer simulation of the development of dish-shaped deepenings by orientation-dependent etching of {100} silicon, 259
Oscillation
application of oscillation phenomenon in $Fe/H_3PO_4–H_2O_2$ system to a thermal sensor, 231
Oscillator circuit
investigation of the magnetosensitivity of a dual-emitter dual-base structure in oscillator mode of operation, 19

Package stresses
on-chip decoupling zone for package-stress reduction, 149
Phase-locked loop
integrated silicon capacitive accelerometer with PLL servo technique, 209
Photodetectors
photodetectors based on metal–tunnel insulator–semiconductor structures, 7
study of MSM photodetector fabricated on porous silicon, 253
Photothermal excitation
photothermal excitation and self-excitation of silicon microresonators, 141
Piezoresistance
piezoresistive accelerometer with overload protection and low cross-sensitivity, 201
Polymer films
polymer films as a material for sensors, 1
Position-sensitive detector
integrated photocapacitive position-sensitive detector made in CMOS technology, 117
Pressure sensor
vertical-membrane optical-fiber pressure sensor, 49
semiconductor string pressure sensor, 125
on-chip decoupling zone for package-stress reduction, 149

Quartz-oscillator method
measurement of 0–1 ml volumes using the procedure of capacitive-dependent crystals, 111

Regional observation
regional observability and sensor structures, 95

Self-excitation
photothermal excitation and self-excitation of silicon microresonators, 141
Semiconductor string
semiconductor string pressure sensor, 125
Sensor materials
polymer films as a material for sensors, 1
Sensors
regional observability and sensor structures, 95
the fundamentals of sensors, 103
Silicon
photothermal excitation and self-excitation of silicon microresonators, 141
finite-element modelling and characterization of a silicon condenser microphone with a highly perforated backplate, 191
integrated silicon capacitive accelerometer with PLL servo technique, 209
a monolithic Si UV detector–dosimeter, 225
study of MSM photodetector fabricated on porous silicon, 253
computer simulation of the development of dish-shaped deepenings by orientation-dependent etching of {100} silicon, 259
SOI structures
thin SOI structures for sensing and integrated circuit applications, 241

Tellurium
magnetic-field sensor using plastic optical fiber and polycrystalline CdMnTe, 25
Thermal sensor
application of oscillation phenomenon in $Fe/H_3PO_4–H_2O_2$ system to a thermal sensor, 231
Thermistors
structural, electrical and infrared optical properties of vanadium pentoxide (V_2O_5) thick-film thermistors, 59
Thermodynamic basis
the fundamentals of sensors, 103

Ultraviolet detector
a monolithic Si UV detector–dosimeter, 225
Ultraviolet dosimeter
a monolithic Si UV detector–dosimeter, 225

Vanadium
structural, electrical and infrared optical properties of vanadium pentoxide (V_2O_5) thick-film thermistors, 59
Volume measurement
measurement of 0–1 ml volumes using the procedure of capacitive-dependent crystals, 111

Xy-stage
comb actuators for *xy*-microstages, 83